

Bay Area Air Quality Management District

939 Ellis Street
San Francisco, CA 94109
(415) 771-6000

Final

MAJOR FACILITY REVIEW PERMIT

Issued To:

READ-RITE CORPORATION

Facility #A2124

Facility Address:

345 Los Coches Road
Milpitas, CA 95035

Mailing Address:

345 Los Coches Road
Milpitas, CA 95035

Responsible Official

Mike Klyszeiko,
Executive Vice President of Operations
(510) 683 6100

Facility Contact

Scott Hess,
Facilities Project Manger
(510) 683 7688

Type of Facility: Manufacturing
Primary SIC: 3679
Product: Computer disk drive read/write heads

BAAQMD Permit Division Contact:
Julian Elliot

ISSUED BY THE BAY AREA AIR QUALITY MANAGEMENT DISTRICT

Signed by Peter Hess for Ellen Garvey
Ellen Garvey, Executive Officer/Air Pollution Control Officer

March 22, 2000
Date

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I. STANDARD CONDITIONS

A. Administrative Requirements

The permit holder shall comply with all applicable requirements in the following regulations:

BAAQMD Regulation 1 - General Provisions and Definitions

(as amended by the District Board on 10/7/98);

SIP Regulation 1 - General Provisions and Definitions

(as approved by EPA through 8/27/99);

BAAQMD Regulation 2, Rule 1 - Permits, General Requirements

(as amended by the District Board on 10/7/98);

SIP Regulation 2, Rule 1 - Permits, General Requirements

(as approved by EPA through 2/25/99);

BAAQMD Regulation 2, Rule 2 - Permits, New Source Review

(as amended by the District Board on 10/7/98);

SIP Regulation 2, Rule 2 - Permits, New Source Review and Prevention of Significant Deterioration

(as approved by EPA through 2/25/99);

BAAQMD Regulation 2, Rule 4 - Permits, Emissions Banking

(as amended by the District Board on 10/7/98); and

SIP Regulation 2, Rule 4 - Permits, Emissions Banking

(as approved by EPA through 2/25/99).

B. Conditions to Implement Regulation 2, Rule 6, Major Facility Review

1. This Major Facility Review Permit was issued on March 22, 2000 and expires on February 28, 2005. The permit holder shall submit a complete application for renewal of this Major Facility Review Permit no later than August 31, 2004 and no earlier than February 28, 2004. **If a complete application for renewal has not been submitted in accordance with these deadlines, the facility may not operate after February 28, 2005.** (Regulation 2-6-307, 404.2, & 409.6; MOP Volume II, Part 3, §4.2)
2. The permit holder shall comply with all conditions of this permit. The permit consists of this document and all appendices. Any non-compliance with the terms and conditions of this permit will constitute a violation of the law and will be grounds for enforcement action; permit termination, revocation and re-issuance, or modification; or denial of a permit renewal application. (Regulation 2-6-307; MOP Volume II, Part 3, §4.11)
3. In the event any enforcement action is brought as a result of a violation of any term or condition of this permit, the fact that it would have been necessary for the permittee to halt or reduce the permitted activity in order to maintain compliance with such term or condition shall not be a defense to such enforcement action. (MOP Volume II, Part 3, §4.11)
4. This permit may be modified, revoked, reopened and reissued, or terminated for cause. (Regulation 2-6-307, 409.8, 415; MOP Volume II, Part 3, §4.11)
5. The filing of a request by the facility for a permit modification, revocation and re-issuance, or termination, or of a notification of planned changes or anticipated non-

I. Standard Conditions

compliance does not stay the applicability of any permit condition. (Regulation 2-6-409.7; MOP Volume II, Part 3, §4.11)

6. This permit does not convey any property rights of any sort, nor any exclusive privilege. (Regulation 2-6-409.7; MOP Volume II, Part 3, §4.11)
7. The permit holder shall supply within 30 days any information that the District requests in writing to determine whether cause exists for modifying, revoking and reissuing, or terminating the permit or to determine compliance with the permit. (Regulation 1-441, Regulation 2-6-409.4 & 501; MOP Volume II, Part 3, §4.11)
8. Any records required to be maintained pursuant to this permit which the permittee considers to contain proprietary or trade secret information shall be prominently designated as such. Copies of any such proprietary or trade secret information which are provided to the District shall be maintained by the District in a locked confidential file, provided, however, that requests from the public for the review of any such information shall be handled in accordance with the District's procedures set forth in Section 11 of the District Administrative Code. (Regulation 2-6-419; MOP Volume II, Part 3, §4.11)
9. Proprietary or trade secret information provided to EPA will be subject to the requirements of 40 CFR Part 2, Subpart B - Public Information, Confidentiality of Business Information. (40 CFR Part 2)
10. The emissions inventory submitted with the application for this Major Facility Review Permit is an estimate of actual emissions for the time period stated and is included only as one means of determining applicable requirements for emission sources. It does not establish, or constitute a basis for establishing, any new emission limitations. (MOP Volume II, Part 3, §4.11)

C. Requirement to Pay Fees

The permit holder shall pay annual fees in accordance with District Regulation 3, including Schedule P. (Regulation 2-6-402 & 409.13, Regulation 3; MOP Volume II, Part 3, §4.12)

D. Inspection and Entry

Access to Facility: The permit holder shall provide reasonable access to the facility and equipment which is subject to this permit to the APCO and/or to his or her designee. (Regulation 1-440, Regulation 2-6-409.3; MOP Volume II, Part 3, §4.14)

E. Records

Notwithstanding the specific wording in any requirement, all records for federally enforceable requirements shall be maintained for at least five years from the date of entry. (Regulation 2-6-501, Regulation 3; MOP Volume II, Part 3, §4.7)

F. Monitoring Reports

All required monitoring reports must be submitted to the District at least once every six months, except where an applicable requirement specifies more frequent reporting. The first reporting period for this permit shall be March 22, 2000 to August 31, 2000. The report shall be submitted by September 30, 2000. Subsequent reports shall be for the following periods: September 1st through February 28th or 29th and March 1st through

I. Standard Conditions

August 31st, and are due on the last day of the month after the end of the reporting period. All instances of non-compliance shall be clearly identified in these reports. The reports shall be certified by the responsible official as true, accurate, and complete. In addition, all instances of non-compliance with the permit shall be reported in writing to the District's Compliance and Enforcement Division within 10 calendar days of the discovery of the incident. Within 30 calendar days of the discovery of any incident of non-compliance, the facility shall submit a written report including the probable cause of non-compliance and any corrective or preventative actions. The reports shall be sent to the following address:

Director of Compliance and Enforcement
Bay Area Air Quality Management District
939 Ellis Street
San Francisco, CA 94109
Attn: Title V Reports

(Regulation 2-6-502, Regulation 3; MOP Volume II, Part 3, §4.7)

G. Compliance Certification

Compliance certifications shall be submitted annually by the responsible official of this facility to the Bay Area Air Quality Management District and to the Environmental Protection Agency. The certification period will be March 1st to February 28th or 29th. The certification shall be submitted by March 31st of each year. The certification must list each applicable requirement, the compliance status, whether compliance was continuous or intermittent, the method used to determine compliance, and any other specific information required by the permit. The permit holder may satisfy this requirement through submittal of District-generated Compliance Certification forms. The certification should be directed to the District's Compliance and Enforcement Division at the address above, and a copy of the certification should be sent to the Environmental Protection Agency at the following address:

Director of the Air Division
USEPA, Region IX
75 Hawthorne Street
San Francisco, CA 94105
Attention: Air-3

(MOP Volume II, Part 3, §4.5 and 4.15)

H. Emergency Provisions

1. The permit holder may seek relief from enforcement action in the event of a breakdown, as defined by Regulation 1-208 of the District's Rules and Regulations, by following the procedures contained in Regulations 1-431 and 1-432. The District will thereafter determine whether breakdown relief will be granted in accordance with

I. Standard Conditions

Regulation 1-433. (MOP Volume II, Part 3, §4.8)

2. The permit holder may seek relief from enforcement action for a violation of any of the terms and conditions of this permit caused by conditions beyond the permit holder's reasonable control by applying to the District's Hearing Board for a variance pursuant to Health and Safety Code Section 42350. The Hearing Board will determine after notice and hearing whether variance relief should be granted in accordance with the procedures and standards set forth in Health and Safety Code Section 42350 et seq. Any variance granted by the Hearing Board from any term or condition of this permit which lasts longer than 90 days will be subject to EPA approval. (MOP Volume II, Part 3, §4.8)
3. Notwithstanding the foregoing, the granting by the District of breakdown relief or the issuance by the Hearing Board of a variance will not provide relief from federal enforcement. (MOP Volume II, Part 3, §4.8)

I. Severability

In the event that any provision of this permit is invalidated by a court or tribunal of competent jurisdiction, or by the Administrator of the EPA, all remaining portions of the permit shall remain in full force and effect. (Regulation 2-6-409.5; MOP Volume II, Part 3, §4.10)

II. EQUIPMENT

Table II A – Permitted Sources

Each of the following sources has been issued a permit to operate pursuant to the requirements of BAAQMD Regulation 2, Permits.

S#	Description	Make or Type	Model	Capacity
9	Waste Solvent Tank	fixed roof	NA	1200 gallons
20	Wafer Fabrication Operation (Wafer Fab)	various photolithography tools and operations, described below	see below	see below
	“PRS-03” positive photoresist stripping solvent station	7 solvent sinks	custom	(3) heated 3.3 gal NMP sinks; (2) 3.3 gal NMP sinks; (1) 3.3 gal IPA sink; (1) 3.3 gal acetone sink
	“PRS-04” positive photoresist stripping solvent station	7 solvent sinks	custom	(3) heated 3.3 gal NMP sinks; (3) 3.3 gal NMP sinks; (1) 3.3 gal IPA sink
	“PRS-01” negative photoresist stripping solvent station	2 solvent sinks	custom	(2) 5.0 gal NMP sinks
	“STI-01” spray resist stripper	Semitool		8 gal NMP capacity
	“WB-05” gap lift-off/mask clean solvent station	4 solvent sinks	custom	(2) heated 3.3 gal NMP sinks; (1) 3.3 gal NMP sink; (1) 3.3 gal IPA sink
	“WB-11” mannitol wafer clean solvent station	2 solvent sinks	custom	(1) 2.8 gal acetone sink; (1) 2.8 gal IPA sink
	“SOL-2” wipe cleaning station	acetone and IPA	NA	NA
	“SOL-3” wipe cleaning station	acetone and IPA	NA	NA
	“RR Coat-05”, “RR Coat-06”	SVG	2-track photoresist applicator	NA

II. Equipment

Table II A – Permitted Sources

Each of the following sources has been issued a permit to operate pursuant to the requirements of BAAQMD Regulation 2, Permits.

S#	Description	Make or Type	Model	Capacity
20	“RR Coat-09”	Fairchild	1-track photoresist applicator	NA
	“RR Coat-10”	Fairchild	1-track photoresist applicator	NA
	“RR Coat-11”	Fairchild	1-track photoresist applicator	NA
	“RR Coat-12”	Fairchild	1-track photoresist applicator	NA
30	“HSA/HGA” wipe cleaning operation (Bldg 3)	acetone and IPA	NA	NA
39	“AEP-7035” solvent station (Slider Fab)	AEP	7035	(2) 8.0 gal NMP sinks
50	“SSEC-02” Spray Developer/Stripper for slider R&D (Slider Fab)	SSEC	10XPi Evergreen developer	NA
52	“Slider R&D debond sink” solvent station (Slider Fab)	Bettcher Process Services	9 foot debond station	(3) 3.8 gal NMP sink; (2) 5.5 gal acetone sink; (1) 3.8 gal IPA sink;
53	“Slider R&D” wipe cleaning (Slider Fab)	acetone and IPA	NA	NA
54	“AIO coater” for slider R&D (Slider Fab)	AIO Corporation	single track coater	NA
55	Forward Technology vapor debonder (Slider Fab)	Forward Technology	SA 2/18 12 12	(2) 18” x 12” x 12” (11.2 gal) sinks holding NMP and either IPA or acetone
56	Intevac Head Coater (Building 3)	Intevac	HC1G100A	NA
57	"AIO coater #2" (Slider Fab)	AIO Corporation	single track coater	NA

III. GENERALLY APPLICABLE REQUIREMENTS

The permit holder shall comply with all applicable requirements, including those specified in the BAAQMD and SIP Rules and Regulations and other federal requirements cited below. These requirements apply in a general manner to the facility and/or to sources exempt from the requirement to obtain a District Permit to Operate. The District has determined that these requirements would not be violated under normal, routine operations, and that no additional periodic monitoring or reporting to demonstrate compliance is warranted. In cases where a requirement, in addition to being generally applicable, is also specifically applicable to one or more sources, the requirement and the source are also included in Section IV, Source-Specific Applicable Requirements, of this permit.

The dates in parenthesis in the Title column identify the versions of the regulations being cited and are, as applicable:

1. BAAQMD regulation(s): The date(s) of adoption or most recent amendment of the regulation by the District Board
2. Any federal requirement, including a version of a District regulation that has been approved into the SIP: The most recent date of EPA approval of any portion of the rule, encompassing all actions on the rule through that date

The full language of SIP requirements is included in Appendix A of this permit if the SIP requirement is different from the current BAAQMD requirement.

NOTE:

There are differences between the current BAAQMD rule and the version of the rule in the SIP. For specific information, contact the District's Rule Development Section of the Enforcement Division. All sources must comply with both versions of the rule until US EPA has reviewed and approved the District's revision of the regulation.

**Table III
 Generally Applicable Requirements**

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)
BAAQMD Regulation 1	General Provisions and Definitions (10/7/98)	N
SIP Regulation 1	General Provisions and Definitions (8/27/99)	Y
BAAQMD Regulation 4	Air Pollution Episode Plan (3/20/91)	N
SIP Regulation 4	Air Pollution Episode Plan (8/06/90)	Y

III. Generally Applicable Requirements

Table III
Generally Applicable Requirements

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)
BAAQMD Regulation 6	Particulate Matter and Visible Emissions (12/19/90)	Y
BAAQMD Regulation 7	Odorous Substances (3/17/82)	N
BAAQMD Regulation 8, Rule 1	Organic Compounds - General Provisions (6/15/94)	Y
BAAQMD Regulation 8, Rule 3	Organic Compounds - Architectural Coatings (12/20/95)	Y
BAAQMD Regulation 8, Rule 49	Organic Compounds - Aerosol Paint Products (12/20/95)	N
SIP Regulation 8, Rule 49	Organic Compounds - Aerosol Paint Products (3/22/95)	Y
BAAQMD Regulation 8, Rule 51	Organic Compounds - Adhesive and Sealant Products (12/20/95)	N
BAAQMD Regulation 11, Rule 2	Hazardous Pollutants - Asbestos Demolition, Renovation and Manufacturing (12/4/91)	Y
BAAQMD Regulation 12, Rule 4	Miscellaneous Standards of Performance - Sandblasting (7/11/90)	Y
EPA Regulation 40 CFR 82	Protection of Stratospheric Ozone (2/21/95)	
Subpart F, 40 CFR 82.156	Leak Repair	Y
Subpart F, 40 CFR 82.161	Certification of Technicians	Y
Subpart F, 40 CFR 82.166	Records of Refrigerant	Y

IV. SOURCE-SPECIFIC APPLICABLE REQUIREMENTS

The permit holder shall comply with all applicable requirements, including those specified in the BAAQMD and SIP Rules and Regulations and other federal requirements cited below. The requirements cited in the following tables apply in a specific manner to the indicated source(s).

The dates in parenthesis in the Title column identify the versions of the regulations being cited and are, as applicable:

1. BAAQMD regulation(s): The date(s) of adoption or most recent amendment of the regulation by the District Board
2. Any federal requirement, including a version of a District regulation that has been approved into the SIP: The most recent date of EPA approval of any portion of the rule, encompassing all actions on the rule through that date

The full text of each permit condition cited is included in Section VI, Permit Conditions, of this permit. The full language of SIP requirements is included in Appendix A of this permit if the SIP requirements are different from the current BAAQMD requirements. All other text may be found in the regulations themselves.

Table IV – A
Source-specific Applicable Requirements
S9 – WASTE SOLVENT TANK, 1200 GALLONS

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 5	Storage of Organic Liquids (1/20/93)		
8-5-301	Storage Tanks Smaller Than 150 Cubic Meters (39,626 gallons)		
8-5-301.1	Submerged fill pipe	Y	
8-5-501	Records of liquids stored and true vapor pressures	Y	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	

IV. Source-specific Applicable Requirements

Table IV – A
Source-specific Applicable Requirements
S9 – WASTE SOLVENT TANK, 1200 GALLONS

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16870			
Part 1	Applicability of Regulation 8, Rule 5 and Condition 13311, Parts 3, 4 and 5 (basis: Regulation 8, Rule 5, Regulation 2-2-302)	Y	

Table IV – B
Source-specific Applicable Requirements
S20 – WAFER FABRICATION AREA

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 30	Organic Compounds – Semiconductor Wafer Fabrication Operations (10/7/98)		
8-30-304	Solvent Sink Requirements		
8-30-304.1	Cover requirement	N	
8-30-304.2	Capacity labeling requirement	N	
8-30-304.3	Storage, disposal requirement	N	
8-30-304.4	Liquid leak repair	N	
8-30-304.5	Freeboard ratio requirement	N	
8-30-305	Solvent Spray Station requirements		
8-30-305.1	Sealed design requirement	N	
8-30-305.2	Liquid leak repair requirement	N	
8-30-305.3	Emission limit	N	
8-30-307	Fab Area Wipe Cleaning (solvent VOC content limit)	N	
8-30-501	Annual Reporting		

IV. Source-specific Applicable Requirements

Table IV – B
Source-specific Applicable Requirements
S20 – WAFER FABRICATION AREA

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
8-30-501.1	Recordkeeping requirement	N	
8-30-504	Solvent Spray Station and Vapor Station Emissions	N	
SIP Regulation 8, Rule 30	Organic Compounds – Semiconductor Manufacturing Operations (6/15/94)		
8-30-304	Solvent Cleaning Station Limits		
8-30-304.1	Cover requirement	Y	
8-30-304.2	Freeboard ratio requirement for unheated stations	Y	
8-30-304.3	Cover and freeboard ratio requirement for heated stations	Y	
8-30-304.4	Capacity marking requirement	Y	
8-30-304.5	Storage, disposal requirement	Y	
8-30-304.6	Proper operation, maintenance requirement	Y	
8-30-304.7	Liquid leak repair	Y	
8-30-501	Annual Reporting		
8-30-501.1	Recordkeeping requirement	Y	
8-30-501.2	Waste solvent recordkeeping requirement	Y	
8-30-502	Records		
8-30-502.1	Weekly records for 8-30-110 exemption limit	Y	
8-30-502.2	Record retention requirement	Y	
BAAQMD Condition 13311			
Part 1	Applicability (basis: Regulation 2, Rule 1)	Y	
Part 2a	Gross photoresist usage limit (basis: cumulative increase)	Y	
Part 2b	VOC limit for photoresist developers (basis: cumulative increase)	Y	
Part 2c	Solvent station solvent usage limit (basis: cumulative increase)	Y	
Part 2d	Cleanup solvent usage limit (basis: cumulative increase)	Y	
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	

IV. Source-specific Applicable Requirements

Table IV – C
Source-specific Applicable Requirements
S30 – “HSA/HGA” WIPE CLEANING OPERATION (BLDG 3)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (9/16/98)		
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, annual records of makeup solvent use	N	
8-16-501.5	Record retention	N	
SIP Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (6/15/94)		
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, quarterly records of makeup solvent use	Y ¹	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 13313			
Part 1	Applicability of Regulation 8, Rule 16 and Condition 13311, Parts 3, 4 and 5 (basis: Regulation 8-16-501, Regulation 2-2-302)	Y	
Part 2	Net solvent usage limits (basis: cumulative increase)	Y	
Part 3	Monthly net solvent usage records (basis: cumulative increase)	Y	

IV. Source-specific Applicable Requirements

Table IV – D
Source-specific Applicable Requirements
S39 – “AEP 7035” SOLVENT STATION (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (9/16/98)		
8-16-303	Cold Cleaner Requirements		
8-16-303.1	General Operating Requirements		
8-16-303.1.1	proper operation and maintenance	Y	
8-16-303.1.2	leak repair	Y	
8-16-303.1.3	solvent storage and disposal	Y	
8-16-303.1.4	waste solvent residues	Y	
8-16-303.1.5	devices used to reduce evaporation	Y	
8-16-303.1.6	prohibition of solvent spray unless abated or enclosed	N	
8-16-303.2	Cold Cleaner Operating Requirements	Y	
8-16-303.3	Cold Cleaner General Equipment Requirements	Y	
8-16-303.4	Cold Cleaner Abatement Requirements		
8-16-303.4.1	freeboard ratio at least 0.75, and associated maximum capacity marking in sink	Y	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, annual records of makeup solvent use	N	
8-16-501.5	Record retention	Y	
SIP Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (6/15/94)		
8-16-303	Cold Cleaner Requirements		
8-16-303.1	General Operating Requirements		
8-16-303.1.1	proper operation and maintenance	Y	
8-16-303.1.2	leak repair	Y	
8-16-303.1.3	solvent storage and disposal	Y	
8-16-303.1.4	waste solvent residues	Y	
8-16-303.1.5	devices used to reduce evaporation	Y	
8-16-303.1.6	prohibition of solvent spray unless abated	Y	
8-16-303.4	Cold Cleaner Abatement Requirements	Y	

IV. Source-specific Applicable Requirements

Table IV – D
Source-specific Applicable Requirements
S39 – “AEP 7035” SOLVENT STATION (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
8-16-303.4.1	freeboard ratio at least 0.75, and associated maximum capacity marking in sink	Y	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, quarterly records of makeup solvent use	Y ¹	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 15314			
Part 1	Applicability of Regulation 8, Rule 16 and Condition 13311, Parts 3, 4 and 5 (basis: Regulation 8, Rule 16, Regulation 2-2-302)	Y	
Part 2	Monthly net solvent usage limit (basis: cumulative increase)	Y	
Part 3	Monthly net solvent usage records (basis: cumulative increase)	Y	

Table IV – E
Source-specific Applicable Requirements
S50 – “SSEC-01” DEVELOPER/STRIPPER FOR SLIDER R&D – (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (9/16/98)		
8-16-303	Cold Cleaner Requirements		
8-16-303.1	General Operating Requirements		
8-16-303.1.1	proper operation and maintenance	Y	

IV. Source-specific Applicable Requirements

Table IV – E
Source-specific Applicable Requirements
S50 – “SSEC-01” DEVELOPER/STRIPPER FOR SLIDER R&D – (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
8-16-303.1.2	leak repair	Y	
8-16-303.1.3	solvent storage and disposal	Y	
8-16-303.1.4	waste solvent residues	Y	
8-16-303.1.5	devices used to reduce evaporation	Y	
8-16-303.1.6	prohibition of solvent spray unless abated or enclosed	N	
8-16-303.2	Cold Cleaner Operating Requirements	Y	
8-16-303.3	Cold Cleaner General Equipment Requirements	Y	
8-16-303.4	Cold Cleaner Abatement Requirements		
8-16-303.4.5	enclosed design	N	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, annual records of makeup solvent use	N	
8-16-501.4	Monthly records for enclosed solvent records	N	
8-16-501.5	Record retention	Y	
SIP Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (6/15/94)		
8-16-303	Cold Cleaner Requirements		
8-16-303.1	General Operating Requirements		
8-16-303.1.1	proper operation and maintenance	Y	
8-16-303.1.2	leak repair	Y	
8-16-303.1.3	solvent storage and disposal	Y	
8-16-303.1.4	waste solvent residues	Y	
8-16-303.1.5	devices used to reduce evaporation	Y	
8-16-303.1.6	prohibition of solvent spray unless abated	Y	
8-16-303.4	Cold Cleaner Abatement Requirements	Y	
8-16-303.4.5	enclosed design in which cover or door opens only when the dry part is entering or exiting the cold cleaner unless the cleaner is airtight	Y	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, quarterly records of makeup solvent use	Y ¹	

IV. Source-specific Applicable Requirements

Table IV – E
Source-specific Applicable Requirements
S50 – “SSEC-01” DEVELOPER/STRIPPER FOR SLIDER R&D – (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16859			
Part 1	Applicability of Regulation 8, Rule 16 and Condition 13311, Parts 3, 4 and 5 (basis: Regulation 8, Rule 16, Regulation 2-2-302)	Y	
Part 2	Monthly net solvent usage limits (basis: cumulative increase)	Y	
Part 3	Monthly net solvent usage records (basis: cumulative increase)	Y	

1 This section has been removed from BAAQMD Regulations because it has been superseded. Nevertheless, the source must comply with this regulation until US EPA has reviewed and approved the District’s revision of the regulation.

IV. Source-specific Applicable Requirements

Table IV – F
Source-specific Applicable Requirements
S52 – “BETTCHEr DEBOND” SOLVENT STATION – (SLIDER R&D)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (9/16/98)		
8-16-303	Cold Cleaner Requirements		
8-16-303.1	General Operating Requirements		
8-16-303.1.1	proper operation and maintenance	Y	
8-16-303.1.2	leak repair	Y	
8-16-303.1.3	solvent storage and disposal	Y	
8-16-303.1.4	waste solvent residues	Y	
8-16-303.1.5	devices used to reduce evaporation	Y	
8-16-303.1.6	prohibition of solvent spray unless abated or enclosed	N	
8-16-303.2	Cold Cleaner Operating Requirements	Y	
8-16-303.3	Cold Cleaner General Equipment Requirements	Y	
8-16-303.4	Cold Cleaner Abatement Requirements		
8-16-303.4.1	freeboard ratio at least 0.75, and associated maximum capacity marking in sink	Y	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, annual records of makeup solvent use	N	
8-16-501.5	Record retention	Y	
SIP Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (6/15/94)		
8-16-303	Cold Cleaner Requirements		
8-16-303.1	General Operating Requirements		
8-16-303.1.1	proper operation and maintenance	Y	
8-16-303.1.2	leak repair	Y	
8-16-303.1.3	solvent storage and disposal	Y	
8-16-303.1.4	waste solvent residues	Y	
8-16-303.1.5	devices used to reduce evaporation	Y	
8-16-303.1.6	prohibition of solvent spray unless abated	Y	
8-16-303.4	Cold Cleaner Abatement Requirements	Y	

IV. Source-specific Applicable Requirements

Table IV – F
Source-specific Applicable Requirements
S52 – “BETTCHEr DEBOND” SOLVENT STATION – (SLIDER R&D)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
8-16-303.4.1	freeboard ratio at least 0.75, and associated maximum capacity marking in sink	Y	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, quarterly records of makeup solvent use	Y ¹	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16860			
Part 1	Applicability of Regulation 8, Rule 16 and Condition 13311, Parts 3,4 and 5 (basis: Regulation 8, Rule 16, Regulation 2-2-302)	Y	
Part 2	Annual net solvent usage limits (basis: cumulative increase)	Y	
Part 3	Freeboard ratio requirement (basis: BACT)	Y	
Part 4	Monthly net solvent usage records (basis: cumulative increase)	Y	

¹ This section has been removed from BAAQMD Regulations because it has been superseded. Nevertheless, the source must comply with this regulation until US EPA has reviewed and approved the District’s revision of the regulation.

IV. Source-specific Applicable Requirements

Table IV – G
Source-specific Applicable Requirements
S53 – SLIDER R&D WIPE CLEANING (BLDG 1)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (9/16/98)		
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, annual records of makeup solvent use	N	
8-16-501.5	Record retention	N	
SIP Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (6/15/94)		
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, quarterly records of makeup solvent use	Y ¹	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16861			
Part 1	Applicability of Regulation 8, Rule 16 and Condition 13311, Parts 3,4 and 5 (basis: Regulation 8-16-501, Regulation 2-2-302)	Y	
Part 2	Annual net solvent usage limits (basis: cumulative increase)	Y	
Part 3	Wipe cleaning requirements (basis: BACT)	Y	
Part 4	Monthly net solvent usage records (basis: cumulative increase)	Y	

¹ This section has been removed from BAAQMD Regulations because it has been superseded. Nevertheless, the source must comply with this regulation until US EPA has reviewed and approved the District's revision of the regulation.

IV. Source-specific Applicable Requirements

Table IV – H
Source-specific Applicable Requirements
S54 - “AIO COATER” FOR SLIDER R&D – (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 4	Organic Compounds – General Solvent and Surface Coating Operations (5/15/96)		
8-4-302	Solvents and Surface Coating Requirements		
8-4-302.1	5 ton/yr VOC emission limit	N	
8-4-312	Solvent Evaporative Loss Minimization		
8-4-312.1	Closed storage and disposal containers	N	
8-4-312.2	Cleanup solvent collection	N	
8-4-312.3	Closed containers for solvents, coatings	N	
8-4-501	Recordkeeping Requirements		
8-4-501.1	Current list of coatings and solvents	Y	
8-4-501.2	Annual records of coating and cleanup solvent use	Y	
8-4-501.4	Record Retention (24 months)	N	
SIP Regulation 8, Rule 4	Organic Compounds – General Solvent and Surface Coating Operations (6/1/94)	Y	
8-4-302	Limitation on Solvents and Surface Coatings (5 ton/yr POC emission limit)	Y	
8-4-501	Recordkeeping Requirements		
8-4-501.1	Current list of coatings and solvents	Y	
8-4-501.2	Annual records of coating and cleanup solvent use	Y	
8-4-501.4	Record Retention (36 months)	Y ¹	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16862			

IV. Source-specific Applicable Requirements

Table IV – H
Source-specific Applicable Requirements
S54 - “AIO COATER” FOR SLIDER R&D – (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
Part 1	Applicability of Regulation 8, Rule 4 and Condition 13311, Parts 3, 4 and 5 (basis: Regulation 8, Rule 4, Regulation 2-2-302)	Y	
Part 2	Annual net coating, solvent usage limits (basis: cumulative increase)	Y	
Part 3	Monthly coating usage records (basis: cumulative increase)	Y	

1 This section has been removed from BAAQMD Regulations because it has been superseded. Nevertheless, the source must comply with this regulation until US EPA has reviewed and approved the District’s revision of the regulation.

Table IV – I
Source-specific Applicable Requirements
S55 – FORWARD TECHNOLOGY VAPOR DEBONDER – (SLIDER FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (9/16/98)		
8-16-301	Vapor Solvent Cleaner Requirements		
8-16-301.1	General Operating Requirements		
8-16-301.1.1	proper operation and maintenance	Y	
8-16-301.1.2	leak repair	Y	
8-16-301.1.3	solvent storage and disposal	Y	
8-16-301.1.4	waste solvent residues	Y	
8-16-301.1.5	devices used to reduce evaporation	Y	
8-16-301.1.6	solvent carry-out minimization measures	Y	
8-16-301.1.7	solvent spray restrictions or use of enclosed design	N	
8-16-301.1.8	ventilation fan restrictions	Y	
8-16-301.1.9	water separator requirements	Y	
8-16-301.1.10	prohibition against porous material cleaning	Y	
8-16-301.1.11	workload size restriction	Y	

IV. Source-specific Applicable Requirements

Table IV – I
Source-specific Applicable Requirements
S55 – FORWARD TECHNOLOGY VAPOR DEBONDER – (SLIDER FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
8-16-301.2	Vapor Solvent Cleaner General Equipment Requirements	Y	
8-16-301.3	Vapor Solvent Cleaner Safety Switches	N	
8-16-301.3.1	condenser flow switch or water flow loss sensor	N	
8-16-301.3.2	[deleted]	N	
8-16-301.3.3	spray safety switch	Y	
8-16-301.3.4	vapor level control thermostat or vapor concentration exhaust sensor	N	
8-16-301.4	Vapor Solvent Cleaner Abatement Requirements		
8-16-301.4.2	freeboard chiller	Y	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, annual records of makeup solvent use	N	
8-16-501.4	Monthly records for solvent vapor dryers or enclosed solvent records	N	
8-16-501.5	Record retention	Y	
SIP Regulation 8, Rule 16	Organic Compounds – Solvent Cleaning Operations (6/15/94)		
8-16-301	Vapor Solvent Cleaner Requirements		
8-16-301.1	General Operating Requirements		
8-16-301.1.1	proper operation and maintenance	Y	
8-16-301.1.2	leak repair	Y	
8-16-301.1.3	solvent storage and disposal	Y	
8-16-301.1.4	waste solvent residues	Y	
8-16-301.1.5	devices used to reduce evaporation	Y	
8-16-301.1.6	solvent carry-out minimization measures	Y	
8-16-301.1.7	solvent spray restrictions	Y	
8-16-301.1.8	ventilation fan restrictions	Y	
8-16-301.1.9	water separator requirements	Y	
8-16-301.1.10	prohibition against porous material cleaning	Y	
8-16-301.1.11	workload size restriction	Y	
8-16-301.2	Vapor Solvent Cleaner General Equipment Requirements	Y	
8-16-301.3	Vapor Solvent Cleaner Safety Switches	Y	

IV. Source-specific Applicable Requirements

Table IV – I
Source-specific Applicable Requirements
S55 – FORWARD TECHNOLOGY VAPOR DEBONDER – (SLIDER FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
8-16-301.3.1	condenser flow switch	Y	
8-16-301.3.2	[expired]	Y	
8-16-301.3.3	spray safety switch	Y	
8-16-301.3.4	vapor level control thermostat	Y	
8-16-301.4	Vapor Solvent Cleaner Abatement Requirements		
8-16-301.4.2	freeboard chiller	Y	
8-16-501	Solvent Records		
8-16-501.2	Facility-wide, quarterly records of makeup solvent use	Y ¹	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16863			
Part 1	Applicability of Regulation 8, Rule 16 and Condition 13311, Parts 3, 4 and 5 (basis: Regulation 8, Rule 16, Regulation 2-2-302)	Y	
Part 2	Annual net solvent usage limits (basis: cumulative increase)	Y	
Part 3	Freeboard ratio, chiller requirement (basis: BACT)	Y	
Part 4	Monthly net solvent usage records (basis: cumulative increase)	Y	

¹ This section has been removed from BAAQMD Regulations because it has been superseded. Nevertheless, the source must comply with this regulation until US EPA has reviewed and approved the District's revision of the regulation.

IV. Source-specific Applicable Requirements

Table IV – J
Source-specific Applicable Requirements
S56 - “INTEVAC HEAD COATER” – (BLDG 3)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 4	Organic Compounds – General Solvent and Surface Coating Operations (5/15/96)		
8-4-302	Solvents and Surface Coating Requirements		
8-4-302.1	5 ton/yr VOC emission limit	N	
8-4-312	Solvent Evaporative Loss Minimization		
8-4-312.1	Closed storage and disposal containers	N	
8-4-312.2	Cleanup solvent collection	N	
8-4-312.3	Closed containers for solvents, coatings	N	
8-4-501	Recordkeeping Requirements		
8-4-501.1	Current list of coatings and solvents	Y	
8-4-501.2	Annual records of coating and cleanup solvent use	Y	
8-4-501.4	Record Retention (24 months)	N	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16864			
Part 1	Applicability of Regulation 8, Rule 4 (basis: Regulation 8, Rule 4)	N	
Part 2	Annual net coating usage limit (basis: cumulative increase)	N	
Part 3	Monthly coating usage records (basis: cumulative increase)	N	

IV. Source-specific Applicable Requirements

Table IV – K
Source-specific Applicable Requirements
S57 - “AIO COATER #2” – (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
BAAQMD Regulation 8, Rule 4	Organic Compounds – General Solvent and Surface Coating Operations (5/15/96)		
8-4-302	Solvents and Surface Coating Requirements		
8-4-302.1	5 ton/yr VOC emission limit	N	
8-4-312	Solvent Evaporative Loss Minimization		
8-4-312.1	Closed storage and disposal containers	N	
8-4-312.2	Cleanup solvent collection	N	
8-4-312.3	Closed containers for solvents, coatings	N	
8-4-501	Recordkeeping Requirements		
8-4-501.1	Current list of coatings and solvents	Y	
8-4-501.2	Annual records of coating and cleanup solvent use	Y	
8-4-501.4	Record Retention (24 months)	N	
SIP Regulation 8, Rule 4	Organic Compounds – General Solvent and Surface Coating Operations (6/1/94)	Y	
8-4-302	Limitation on Solvents and Surface Coatings (5 ton/yr POC emission limit)	Y	
8-4-501	Recordkeeping Requirements		
8-4-501.1	Current list of coatings and solvents	Y	
8-4-501.2	Annual records of coating and cleanup solvent use	Y	
8-4-501.4	Record Retention (36 months)	Y ¹	
BAAQMD Condition 13311			
Part 3	50 ton/yr POC facility emission limit (basis: Regulation 2-2-302)	Y	
Part 4	50 ton/yr POC facility emission calculation requirement and method (basis: Regulation 2-2-302)	Y	
Part 5	Records (basis: cumulative increase, Regulation 2-2-302)	Y	
BAAQMD Condition 16865			

IV. Source-specific Applicable Requirements

Table IV – K
Source-specific Applicable Requirements
S57 - “AIO COATER #2” – (SLIDER-FAB)

Applicable Requirement	Regulation Title or Description of Requirement	Federally Enforceable (Y/N)	Future Effective Date
Part 1	Applicability of Regulation 8, Rule 4 and Condition 13311, Parts 3, 4 and 5 (basis: Regulation 8, Rule 4, Regulation 2-2-302)	Y	
Part 2	Annual net coating, solvent usage limits (basis: cumulative increase)	Y	
Part 3	Monthly coating usage records (basis: cumulative increase)	Y	

1 This section has been removed from BAAQMD Regulations because it has been superseded. Nevertheless, the source must comply with this regulation until US EPA has reviewed and approved the District’s revision of the regulation.

V. SCHEDULE OF COMPLIANCE

The permit holder shall comply with all applicable requirements cited in this permit. The permit holder shall also comply with applicable requirements that become effective during the term of this permit.

VI. PERMIT CONDITIONS

Any condition that is preceded by an asterisk is not federally enforceable.

Condition # 13311

For S20 – WAFER FABRICATION AREA

- S30 - “HSA/HGA” WIPE CLEANING OPERATION (BLDG 3)
- S39 - “AEP 7035” SOLVENT STATION (SLIDER-FAB)
- S50 – “SSEC-01” DEVELOPER/STRIPPER FOR SLIDER R&D – (SLIDER-FAB)
- S52 – “BETTCHEER DEBOND” SOLVENT STATION – (SLIDER R&D)
- S53 – SLIDER R&D WIPE CLEANING (BLDG 1)
- S54 – “AIO COATER” FOR SLIDER R&D – (SLIDER-FAB)
- S55 – FORWARD TECHNOLOGY VAPOR DEBONDER – (SLIDER FAB)
- S56 – “INTEVAC HEAD COATER” – (BLDG 3)
- S57 – “AIO COATER #2” – (SLIDER-FAB)
- S9 – WASTE SOLVENT TANK, 1200 GALLONS

APPLICATION 20366; READ-RITE CORPORATION; PLANT 2124

- 1a. Equipment in the S20 fab area is subject to the requirements of Regulation 8, Rule 30 and includes all production wafer coating applicators (except dry film applicators which do not require permits), wafer solvent stations and other wafer solvent processors.
- 1b. S20 does not include any "approved emission control device" as discussed in Regulations 8-30-302, 304.1, 304.5.2, 305.1, 305.3, 306.1 or 306.3 and therefore may not use any compliance option which requires the use of such a device.

VI. Permit Conditions

Condition # 13311

For S9, Waste Solvent Tank; S20, Wafer Fabrication Area; S30, HSA/HGA wipe cleaning; S39, AEP 7035 solvent station; S50, "SSEC-01" developer/stripper; S52, "Bettcher Debond" solvent station; S53, Slider R&D wipe cleaning; S54, AIO Coater for slider R&D; S55, Forward Technology Vapor Debonder; S56, Intevac Head Coater; S57, AIO coater #2

- 1c. Wafer coatings which include 1% or more volatile organic compounds (VOC) by weight, and other materials which include 10% or more VOC by weight if unheated or 2.5% or more by weight if heated shall be used only as allowed in Part 2.
[Regulation 8, Rule 16; Regulation 2, Rule 1]
- 2a. Gross usage of positive photoresist shall not exceed 2,937 gallons in any 12 consecutive month period.
[Cumulative Increase]
- 2b. All photoresist developer solutions (positive and dry film) shall have less than 10% VOC by weight and may be used in unlimited quantities.
[Cumulative Increase]
- 2c. The total net usage of equipment cleanup solvent (not solvent used in solvent stations) at all S20 fab equipment shall not exceed 864 gallons in any 12 consecutive month period of IPA or acetone; other solvents shall be used only with the written approval of the District. Unless records are maintained of the amount of waste solvent removed from the site by a certified liquid waste handler, net usage will be assumed to be the same as gross usage.
[Cumulative Increase]
- 2d. Beginning March 1, 2000, the emissions from the use of solvents in solvent stations shall be included in the calculation of facility-wide emissions to verify compliance with the 50 ton/yr POC emission limit in Part 3.
[Cumulative Increase]
3. Because offsets were provided to Read-Rite in Applications 16560 and 20366 from the Small Facility Bank Account, facility-wide POC emissions may not exceed 50 tons in any consecutive 12-month period unless these offsets are first refunded by Read-Rite. Emissions which must be included when determining compliance with this limit include all emissions of POC compounds, as defined in Regulation 2, Rule 1, from all devices and operations which are not exempt from the requirements of Regulation 2-1-301 and 2-1-302. Compliance with this limit shall be verified in accordance with the procedure in Part 4.
[Regulation 2-2-302]

VI. Permit Conditions

Condition # 13311

For S9, Waste Solvent Tank; S20, Wafer Fabrication Area; S30, HSA/HGA wipe cleaning; S39, AEP 7035 solvent station; S50, "SSEC-01" developer/stripper; S52, "Bettcher Debond" solvent station; S53, Slider R&D wipe cleaning; S54, AIO Coater for slider R&D; S55, Forward Technology Vapor Debonder; S56, Intevac Head Coater; S57, AIO coater #2

4. Beginning March 1, 2000, monthly calculations of facility-wide POC emissions shall be performed once per calendar month to verify compliance with Part 3 in accordance with one of the following procedures (a or b):
 - a. Emissions shall be based on gross usage of materials, multiplied by the material density, material POC weight fraction and the appropriate emission factor as listed below. Total emissions are the sum of emissions from each material.

Emission =
(gross usage volume)x(material density)x(POC fraction)x(emission factor)

Emission factors:

cleanup solvent:	100% of net solvent use
solvent station solvents:	30% of gross solvent in materials added to solvent stations
photoresist and other materials applied at spin tracks	90% of gross solvent in materials applied at spin tracks

- b. Emissions shall be based on the total amount of POC compounds used, minus the amount of these POC compounds removed from devices and operations as waste. Total emissions are the sum of emissions from each material.

Emission = (gross usage volume)x(material density)x(POC fraction)
- (removed volume)x(material density)x(POC fraction)

If a material is mixed with any other material during use or during removal, such that the POC content of the waste stream is not known, then the POC

Condition # 13311

VI. Permit Conditions

For S9, Waste Solvent Tank; S20, Wafer Fabrication Area; S30, HSA/HGA wipe cleaning; S39, AEP 7035 solvent station; S50, "SSEC-01" developer/stripper; S52, "Bettcher Debond" solvent station; S53, Slider R&D wipe cleaning; S54, AIO Coater for slider R&D; S55, Forward Technology Vapor Debonder; S56, Intevac Head Coater; S57, AIO coater #2

content will be assumed to be zero, unless the actual POC content is determined through a laboratory analysis method approved by the District.

[Regulation 2-2-302]

5. The following monthly records shall be maintained in a District-approved log:
 - a. type and gross amount of positive photoresist usage
 - b. (beginning March 1, 2000) type and gross amount of solvent usage in solvent stations
 - c. type and net amount of equipment cleanup solvent usage
 - d. an equipment list identifying each device and operation included in S20
 - e. a list of all photoresist developer products in use at S20, with composition data
 - f. monthly calculation of facility-wide POC emissions as described in Part 4, based on material usage for that month and a current list of all materials containing POC compounds, with the data required to perform the calculations in Part 4; beginning March 1, 2000, monthly reports showing calculations and resulting POC emissions shall be provided to the District Manager of Compliance and Enforcement within 30 days of the end of each month.

These records shall be kept for at least 5 years and shall be made available to the District upon request. [Cumulative Increase, Regulation 2-1-403]

VI. Permit Conditions

Condition # 13313

For S30 - “HSA/HGA” WIPE CLEANING OPERATION (BLDG 3):

APPLICATION 10517; READ-RITE CORPORATION; PLANT 2124
CONDITIONS FOR S30

1. The S30 wipe cleaning operation is subject to Regulation 8-16-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.
[Regulation 8, Rule 16, Regulation 2-2-302]
2. Net usage of the following materials at S30 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

IPA, acetone	195 gallons (total)	[Cumulative Increase]
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3. Monthly records of the type and net amount of cleanup solvent usage at S30 shall be kept in a District- approved log. These records shall be kept for at least five years and shall be made available to the District upon request.
[Cumulative Increase]

Condition # 15314

For S39 - “AEP 7035” SOLVENT STATION (SLIDER-FAB):

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S39

1. The S39 solvent station is subject to the requirements of Regulation 8-16-303 (including 8-16-303.4.1) and 8-16-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.
[Regulation 8, Rule 16, Regulation 2-2-302]
2. Net usage of the following materials at S39 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

NMP	345 gallons
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For the purpose of reporting annual usage, net usage and emissions shall be assumed to be equal to 30% of the gross usage amount. If the amount of spent solvent is measured, then net usage and emissions may be based on actual measured values.
[Cumulative Increase]

VI. Permit Conditions

Condition # 15314

For S39 - "AEP 7035" SOLVENT STATION (SLIDER-FAB):

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S39

3. Monthly records of the type and net usage of solvent at S39 shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request. [Cumulative Increase]

Condition # 16859

For S50 - "SSEC-01" DEVELOPER/STRIPPER FOR SLIDER R&D - (SLIDER-FAB):

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S50

1. The S50 spray stripper is subject to the requirements of Regulation 8-16-303 (including 8-16-303.4.5) and 8-16-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds. [Regulation 8, Rule 16, Regulation 2-2-302]

2. Net usage of the following materials at S50 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

NMP	172 gallons
IPA	140 gallons

For the purpose of reporting annual usage, net usage and emissions shall be assumed to be equal to 30% of the gross usage amount. If the amount of spent solvent is measured, then net usage and emissions may be based on actual measured values. [Cumulative Increase]

3. Monthly records of the type and net usage of solvent at S50 shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request. [Cumulative Increase]

VI. Permit Conditions

Condition # 16860

For S52 – “**BETTCHER DEBOND**” SOLVENT STATION – (SLIDER R&D):

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S52

1. The S52 debond station is subject to the requirements of Regulation 8-16-303 (including 8-16-303.4.1) and 8-16-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.
[Regulation 8, Rule 16, Regulation 2-2-302]

2. Net usage of the following materials at S52 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

NMP	1,800 gallons
IPA	180 gallons
acetone	180 gallons

For the purpose of reporting annual usage, net usage and emissions shall be assumed to be equal to 30% of the gross usage amount. If the amount of spent solvent is measured, then net usage and emissions may be based on actual measured values.
[Cumulative Increase]

3. S52 shall operate with a freeboard ratio of at least 1.0 (as defined in Regulation 8, Rule 16) on all solvent sinks, and sinks shall be covered at all times, except when access to the sinks is required. [BACT]
4. Monthly records of the type and net usage of solvent at S52 shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request. [Cumulative Increase]

VI. Permit Conditions

Condition # 16861

For S53 – **SLIDER R&D WIPE CLEANING (BLDG 1)**:

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S53

1. The S53 Slider R&D wipe cleaning operation is subject to the recordkeeping requirements of Regulation 8-16-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.
[Regulation 8, Rule 16, Regulation 2-2-302]
2. Net usage of the following materials at S53 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

IPA	100 gallons	
acetone	100 gallons	[Cumulative Increase]
3. Wipe cleaning solvent at S53 shall be applied from squeeze bottles to limit solvent evaporation and prevent over-use. Solvent shall be handled in accordance with the requirements of Regulation 8-4-312 to minimize solvent loss.
[BACT]
4. Monthly records of the type and net usage of solvent at S53 shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request.
[Cumulative Increase]

VI. Permit Conditions

Condition # 16862

For S54 – “AIO COATER” FOR SLIDER R&D – (SLIDER-FAB):

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S54

1. The S54 coater is subject to the requirements of Regulation 8-4-302, 8-4-312 and 8-4-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.

[Regulation 8, Rule 4, Regulation 2-2-302]

- 2a. Net usage of the following materials at S54 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

positive photoresist	5 gallons
edge bead remover	70 gallons
thinner and other solvents except cleanup solvents	70 gallons

For the purpose of reporting annual usage, net usage and emissions shall be assumed to be equal to 90% of the gross usage amount. If the amount of spent solvent is measured, then net usage and emissions may be based on actual measured values.

[Cumulative Increase]

- 2b. Net usage of the following cleanup solvents at S54 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

IPA and acetone	10 gallons (total)
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[Cumulative Increase]

3. Monthly records of the gross usage of photoresist, edge bead remover, dispensed solvents and cleanup solvent shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request.

[Cumulative Increase]

VI. Permit Conditions

Condition # 16863

For S55 – **FORWARD TECHNOLOGY VAPOR DEBONDER – (SLIDER FAB):**

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S55

1. The S55 vapor debonder is subject to the requirements of Regulation 8-16-301 and 8-16-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.
[Regulation 8, Rule 16, Regulation 2-2-302]
2. Net usage of the following materials at S55 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

NMP	144 gallons
acetone	553 gallons

[Cumulative Increase, BACT]
3. S55 shall operate with a freeboard ratio of at least 1.0 (as defined in Regulation 8, Rule 16) and with a freeboard chiller operated no warmer than –10 degrees F.
[Regulation 8, Rule 16]
4. Monthly records of the type and net usage of solvent at S55 shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request.
[Cumulative Increase]

VI. Permit Conditions

Condition # 16864

For S56 – “INTEVAC HEAD COATER” – (BLDG 3):

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S56

1. The S56 coater is subject to the requirements of Regulation 8-4-302, 8-4-312 and 8-4-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.

[Regulation 8, Rule 4, Regulation 2-2-302]

2. Net usage of the following materials at S56 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

HFE-7100	16 gallons
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For the purpose of reporting annual usage, net usage and emissions shall be assumed to be equal to 90% of the gross usage amount. If the amount of spent solvent is measured, then net usage and emissions may be based on actual measured values.

[Cumulative Increase]

3. Monthly records of the gross usage of coating at S56 shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request.

[Cumulative Increase]

VI. Permit Conditions

Condition # 16865

For S57 – “AIO COATER #2” – (SLIDER-FAB):

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S57

1. The S57 coater is subject to the requirements of Regulation 8-4-302, 8-4-312 and 8-4-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds.

[Regulation 8, Rule 4, Regulation 2-2-302]

- 2a. Net usage of the following materials at S57 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

positive photoresist	5 gallons
edge bead remover	35 gallons
thinner and other solvents	35 gallons
except cleanup solvents	

For the purpose of reporting annual usage, net usage and emissions shall be assumed to be equal to 90% of the gross usage amount. If the amount of spent solvent is measured, then net usage and emissions may be based on actual measured values.

[Cumulative Increase]

- 2b. Net usage of the following cleanup solvents at S57 shall not exceed the indicated limits in any consecutive 12 month period, and other materials may be used only with prior written approval of the District:

IPA and acetone	10 gallons (total)
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[Cumulative Increase]

3. Monthly records of the gross usage of photoresist, edge bead remover, dispensed solvents and cleanup solvent shall be kept in a District-approved log for at least 5 years and shall be made available to the District upon request.

[Cumulative Increase]

VI. Permit Conditions

Condition # 16870

For S9 – **WASTE SOLVENT TANK, 1200 GALLONS:**

APPLICATION 20366; READ-RITE (MILPITAS); PLANT 2124
CONDITIONS FOR S9

1. S9 is subject to Regulation 8-5-301.1, 8-5-501, and the facility-wide emission limit in Permit Condition 13311 (Parts 3 and 4) for POC compounds. Emissions from S9 shall be estimated using the latest version of EPA's TANKS program or other method approved by the District.

[Regulation 8, Rule 5, Regulation 2-2-302]

VII. APPLICABLE LIMITS & COMPLIANCE MONITORING REQUIREMENTS

This section has been included only to summarize the applicable emission limits contained in Section IV, Source-Specific Applicable Requirements, of this permit. The following tables show the relationship between each emission limit and the associated compliance monitoring provisions, if any. The monitoring frequency indicates whether periodic (P) or continuous (C) monitoring is required. For periodic monitoring, the frequency of the monitoring has also been shown, either annual (A), quarterly (Q), monthly (M), daily (D), or on an event basis (E). No monitoring (N) has been required if the current applicable rule or regulation does not require monitoring, and the operation is unlikely to deviate from the applicable emission limit based upon the nature of the operation.

Table VII – A
Applicable Limits and Compliance Monitoring Requirements
S9 – WASTE SOLVENT TANK, 1200 GALLONS

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 3, 4	P/M	mass balance OR emission calculations

VII. Applicable Limits and Compliance Monitoring Requirements

Table VII – B
Applicable Limits and Compliance Monitoring Requirements
S20 – WAFER FABRICATION AREA

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD 8-30-305.3	N		monthly emissions from solvent spray processors (250 lb/month each)	BAAQMD 8-30-504	P/M	records
	BAAQMD 8-30-307	N		wipe cleaning solution VOC content (no more than 10%)	none	N	none
	BAAQMD Condition 13311, Part 2a	Y		annual photoresist usage (2,937 gal/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	records
	BAAQMD Condition 13311, Part 2b	Y		photoresist developer VOC content (less than 10% by weight)	BAAQMD Condition 13311, Part 4, 5	N	records
	BAAQMD Condition 13311, Part 2c	Y		annual wipe cleaning solvent usage (864 gal/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	records
	BAAQMD Condition 13311, Part 2d	Y		annual solvent station solvent emissions (included under 50 ton/yr VOC facility limit)	BAAQMD Condition 13311, Part 4, 5	P/M	records
	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations

VII. Applicable Limits and Compliance Monitoring Requirements

Table VII – C
Applicable Limits and Compliance Monitoring Requirements
S30 – “HSA/HGA” WIPE CLEANING OPERATION (BLDG 3)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
	BAAQMD Condition 13313, Part 2	Y		annual net solvent usage (195 gal/yr VOC)	BAAQMD Condition 13313, Part 3	P/M	records

Table VII – D
Applicable Limits and Compliance Monitoring Requirements
S39 – “AEP 7035” SOLVENT STATION (SLIDER-FAB)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
	BAAQMD Condition 15314, Part 2	Y		monthly net solvent usage (345 gal/yr VOC)	BAAQMD Condition 15314, Part 4	P/M	records

VII. Applicable Limits and Compliance Monitoring Requirements

Table VII – E
Applicable Limits and Compliance Monitoring Requirements
S50 – “SSEC-01” DEVELOPER/STRIPPER FOR SLIDER R&D – (SLIDER-FAB)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
	BAAQMD Condition 16859, Part 2	Y		monthly net solvent usage (312 gal/yr VOC)	BAAQMD Condition 16859, Part 3	P/M	records

Table VII – F
Applicable Limits and Compliance Monitoring Requirements
S52 – “BETTCHEr DEBOND” SOLVENT STATION – (SLIDER R&D)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
	BAAQMD Condition 16860, Part 2	Y		annual net solvent usage (1,980 gal/yr VOC)*	BAAQMD Condition 16860, Part 4	P/M	records

* although permit condition includes a specific usage allowance for a non-VOC material, this amount is not included in this table

VII. Applicable Limits and Compliance Monitoring Requirements

Table VII – G
Applicable Limits and Compliance Monitoring Requirements
S53 – SLIDER R&D WIPE CLEANING (BLDG 1)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
	BAAQMD Condition 16861, Part 2	Y		annual net solvent usage (100 gal/yr VOC)*	BAAQMD Condition 16861, Part 4	P/M	records

* although permit condition includes a specific usage allowance for a non-VOC material, this amount is not included in this table

Table VII – H
Applicable Limits and Compliance Monitoring Requirements
S54 – “AIO COATER” FOR SLIDER R&D – (SLIDER-FAB)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD 8-4-302.1	N		annual VOC emissions (5 ton/yr)	BAAQMD 8-4-501.2	P/A	records
POC	SIP 8-4-302	Y		annual POC emissions (5 ton/yr)	SIP 8-4-501.2	P/A	records
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
VOC	BAAQMD Condition 16862, Part 2	Y		annual net coating and solvent usage (155 gal/yr VOC)	BAAQMD Condition 16862, Part 3	P/M	records

VII. Applicable Limits and Compliance Monitoring Requirements

Table VII – I
Applicable Limits and Compliance Monitoring Requirements
S55 - FORWARD TECHNOLOGY VAPOR DEBONDER – (SLIDER FAB)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
	BAAQMD Condition 16863, Part 2	Y		annual net solvent usage (144 gal/yr VOC)*	BAAQMD Condition 16863, Part 4	P/M	records

Table VII – J
Applicable Limits and Compliance Monitoring Requirements
S56 – “INTEVAC HEAD COATER” – (BLDG 3)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD 8-4-302.1	N		annual VOC emissions (5 ton/yr)	BAAQMD 8-4-501.2	P/A	records
POC	SIP 8-4-302	Y		annual POC emissions (5 ton/yr)	SIP 8-4-501.2	P/A	records
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
VOC	BAAQMD Condition 16864, Part 2	Y		annual net coating usage (0 gal/yr VOC)*	BAAQMD Condition 16864, Part 3	P/M	records

VII. Applicable Limits and Compliance Monitoring Requirements

* although permit condition includes a specific usage allowance for a non-VOC material, this amount is not included in this table

Table VII – K
Applicable Limits and Compliance Monitoring Requirements
S57 - “AIO COATER #2” – (SLIDER-FAB)

Type of limit	Emission Limit Citation	FE Y/N	Future Effective Date	Emission Limit	Monitoring Requirement Citation	Monitoring Frequency (P/C/N)	Monitoring Type
VOC	BAAQMD 8-4-302.1	N		annual VOC emissions (5 ton/yr)	BAAQMD 8-4-501.2	P/A	records
POC	SIP 8-4-302	Y		annual POC emissions (5 ton/yr)	SIP 8-4-501.2	P/A	records
VOC	BAAQMD Condition 13311, Part 3	Y		annual facility-wide POC emissions (50 ton/yr)	BAAQMD Condition 13311, Part 4, 5	P/M	mass balance OR emission calculations
VOC	BAAQMD Condition 16865, Part 2	Y		annual net coating and solvent usage (85 gal/yr VOC)	BAAQMD Condition 16865, Part 3	P/M	records

VIII. TEST METHODS

The test methods associated with the emission limit of a District regulation are generally found in Section 600 of the regulation. The following table indicates only the test methods associated with the emission limits referenced in Section VII, Applicable Emission Limits & Compliance Monitoring Requirements, of this permit.

**Table VIII
 Test Methods**

Applicable Requirement	Description of Requirement	Acceptable Test Methods
BAAQMD 6-301	Ringelmann opacity limit	Manual of Procedures, Volume I, Evaluation of Visible Emissions
BAAQMD 6-310	Particulate grain loading	Manual of Procedures, Volume IV, ST-15, Particulates Sampling
BAAQMD 8-4-302.1	VOC emission limit	Manual of Procedures, Volume IV, ST-7, Non-Methane Organic Carbon Sampling, or EPA Method 25 or 25A
SIP 8-4-302	VOC emission limit	Manual of Procedures, Volume IV, ST-7, Non-Methane Organic Carbon Sampling, or EPA Method 25 or 25A
BAAQMD Regulation 8-30-307	10% maximum VOC in wipe cleaning solvent	Manual of Procedures, Volume III, Method 31, Determination of Precursor Organic Compounds in Paint Strippers for Aerospace Assembly and Component Coating Operations

IX. GLOSSARY

BAAQMD

Bay Area Air Quality Management District

BACT

Best Available Control Technology

CAA

The federal Clean Air Act

CAAQS

California Ambient Air Quality Standards

CEQA

California Environmental Quality Act

CFR

The Code of Federal Regulations. 40 CFR contains the implementing regulations for federal environmental statutes such as the Clean Air Act. Parts 50-99 of 40 CFR contain the requirements for air pollution programs.

CO

Carbon Monoxide

Cumulative Increase

The sum of permitted emissions from each new or modified source since a specified date pursuant to BAAQMD Rule 2-1-403, Permit Conditions (as amended by the District Board on 7/17/91) and SIP Rule 2-1-403, Permit Conditions (as approved by EPA on 6/23/95). Used to determine whether threshold-based requirements are triggered.

District

The Bay Area Air Quality Management District

EPA

The federal Environmental Protection Agency.

Excluded

Not subject to any District Regulations.

X. Glossary

FE, Federally Enforceable

All limitations and conditions which are enforceable by the Administrator of the EPA including those requirements developed pursuant to 40 CFR Part 51, subpart I (NSR), Part 52.21 (PSD), Part 60, (NSPS), Part 61, (NESHAPs), Part 63 (HAP), and Part 72 (Permits Regulation, Acid Rain), and also including limitations and conditions contained in operating permits issued under an EPA-approved program that has been incorporated into the SIP.

HAP

Hazardous Air Pollutant. Any pollutant listed pursuant to Section 112(b) of the Act. Also refers to the program mandated by Title I, Section 112, of the Act and implemented by both 40 CFR Part 63, and District Regulation 2, Rule 5.

Major Facility

A facility with potential emissions of regulated air pollutants greater than or equal to 100 tons per year, greater than or equal to 10 tons per year of any single hazardous air pollutant, and/or greater than or equal to 25 tons per year of any combination of hazardous air pollutants, or such lesser quantity as determined by the EPA administrator.

MFR

Major Facility Review. The District's term for the federal operating permit program mandated by Title V of the Act and implemented by District Regulation 2, Rule 6.

MOP

The District's Manual of Procedures.

NAAQS

National Ambient Air Quality Standards

NESHAPs

National Emission Standards for Hazardous Air Pollutants. Contained in 40 CFR Part 61.

NMHC

Non-methane Hydrocarbons

NO_x

Oxides of nitrogen.

NSPS

Standards of Performance for New Stationary Sources. Federal standards for emissions from new stationary sources. Mandated by Title I, Section 111 of the Act, and implemented by both 40 CFR Part 60 and District Regulation 10.

X. Glossary

NSR

New Source Review. A federal program for pre-construction review and permitting of new and modified sources of air pollutants for which the District is classified "non-attainment". Mandated by Title I of the Clean Air Act and implemented by 40 CFR Parts 51 and 52 as well as District Regulation 2, Rule 2. (Note: There are additional NSR requirements mandated by the California Clean Air Act.)

Offset Requirement

A New Source Review requirement to provide federally enforceable emission offsets at a specified ratio for the emissions from a new or modified source and any pre-existing cumulative increase minus any onsite contemporaneous emission reduction credits. Applies to emissions of POC, NO_x, PM₁₀, and SO₂.

Phase II Acid Rain Facility

A facility that generates electricity for sale through fossil-fuel combustion and by virtue of certain other characteristics (defined in Regulation 2, Rule 6) is subject to Titles IV and V of the Clean Air Act.

POC

Precursor Organic Compounds

PM

Total Particulate Matter

PM₁₀

Particulate matter with aerodynamic equivalent diameter of less than or equal to 10 microns

PSD

Prevention of Significant Deterioration. A federal program for permitting new and modified sources of air pollutants for which the District is classified "attainment" of the National Air Ambient Quality Standards. Mandated by Title I of the Act and implemented by both 40 CFR Part 52 and District Regulation 2, Rule 2.

SIP

State Implementation Plan. State and District programs and regulations approved by EPA and developed in order to attain the National Air Ambient Quality Standards. Mandated by Title I of the Act.

SO₂

Sulfur dioxide

X. Glossary

Title V

Title V of the federal Clean Air Act. Requires a federally enforceable operating permit program for major and certain other facilities.

VOC

Volatile Organic Compounds

Units of Measure:

bhp	=	brake-horsepower
btu	=	British Thermal Unit
g	=	grams
gal	=	gallon
hp	=	horsepower
hr	=	hour
lb	=	pound
in	=	inches
max	=	maximum
m ²	=	square meter
min	=	minute
mm	=	million
ppmv	=	parts per million, by volume
ppmw	=	parts per million, by weight
psia	=	pounds per square inch, absolute
psig	=	pounds per square inch, gauge
scfm	=	standard cubic feet per minute
yr	=	year

X. APPLICABLE STATE IMPLEMENTATION PLAN

See Attachments